

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: OHMI et al

Serial No.: 10/566,241

Filed: January 30, 2006

For: Microwave Plasma Processing Method, Microwave
Plasma Processing Apparatus, And Its Plasma Head

Art Unit:

Examiner:

PRELIMINARY AMENDMENT

Mail Stop: Amendment (No Fee)
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

October 4, 2006

Sir:

The following amendments and remarks are respectfully requested in
connection with the above-identified application as listed below and as set forth on
the following pages:

Amendments to the Specification;

Amendments to the Claims;

Amendments to the Abstract; and

Remarks are included following the amendments.